

S Santosh Kumar

List of Publications by Year in descending order

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Version: 2024-02-01

19
papers

356
citations

1307594

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h-index

1125743

13
g-index

20
all docs

20
docs citations

20
times ranked

288
citing authors

#	ARTICLE	IF	CITATIONS
1	Design principles and considerations for the "ideal"™ silicon piezoresistive pressure sensor: a focused review. <i>Microsystem Technologies</i> , 2014, 20, 1213-1247.	2.0	172
2	Polysilicon thin film piezoresistive pressure microsensors: design, fabrication and characterization. <i>Microsystem Technologies</i> , 2015, 21, 1949-1958.	2.0	45
3	Experimental evaluation of sensitivity and non-linearity in polysilicon piezoresistive pressure sensors with different diaphragm sizes. <i>Microsystem Technologies</i> , 2016, 22, 83-91.	2.0	30
4	Effect of piezoresistor configuration on output characteristics of piezoresistive pressure sensor: an experimental study. <i>Microsystem Technologies</i> , 2016, 22, 709-719.	2.0	24
5	Development of a MEMS-based barometric pressure sensor for micro air vehicle (MAV) altitude measurement. <i>Microsystem Technologies</i> , 2020, 26, 901-912.	2.0	16
6	Sensitivity and non-linearity study and performance enhancement in bossed diaphragm piezoresistive pressure sensor. , 2015, , .		11
7	Analytical Modelling and FEM Simulation of Capacitive Pressure Sensor for Intraocular Pressure Sensing. <i>IOP Conference Series: Materials Science and Engineering</i> , 0, 404, 012026.	0.6	10
8	Dynamic characterization of bulk micromachined accelerometer using laser doppler vibrometer (LDV). <i>Microsystem Technologies</i> , 2015, 21, 2221-2232.	2.0	7
9	Mathematical Modelling and Comparative Study of Elliptical and Circular Capacitive Pressure Microsensor. <i>Journal of Physics: Conference Series</i> , 2019, 1240, 012068.	0.4	6
10	High-resolution current mode interface for MEMS piezoresistive pressure sensor. <i>AEU - International Journal of Electronics and Communications</i> , 2021, 134, 153707.	2.9	6
11	Design and Simulation of Bulk Micromachined Accelerometer for Avionics Application. <i>Communications in Computer and Information Science</i> , 2013, , 94-99.	0.5	5
12	CCII Based Current Signal Interface for Piezoresistive Pressure Sensor. , 2018, , .		4
13	Modeling and FEM-Based Simulations of Composite Membrane Based Circular Capacitive Pressure Sensor. <i>Lecture Notes in Electrical Engineering</i> , 2020, , 497-506.	0.4	4
14	Fabrication and characterization of pressure sensor, and enhancement of output characteristics by modification of operating pressure range. , 2015, , .		1
15	Comparative study of characteristics of polysilicon pressure sensor with different diaphragm sizes and piezoresistor configurations. <i>AIP Conference Proceedings</i> , 2016, , .	0.4	1
16	A MATLAB program for quick estimation of characteristics of piezoresistive pressure sensors. <i>AIP Conference Proceedings</i> , 2018, , .	0.4	1
17	Realization of MEMS-based silicon cantilever using bulk micromachining. , 2017, , .		0
18	CMOS Compatible Wet Bulk Micromachining for MEMS Applications. , 2019, , .		0

#	ARTICLE	IF	CITATIONS
19	Sensitivity and Linearity Enhancement of Piezoresistive Pressure Sensor Using Stress Concentration Structure. , 2019, , .		0